



Complete 3D Measurement Solution



Complete acces

The S neox Five Axis 3D optical profiler combines a high-accuracy rotational module with the advanced inspection and analysis capabilities of the S neox 3D optical profiler

This enables automatic 3D surface measurements at defined positions which can be combined to create a complete 3D volumetric measurement. S neox 3D measurement technologies cover a wide range of scales, including form (Ai Focus Variation), sub nanometric roughness (Interferometry) or critical dimensions that require high lateral resolution as well as vertical resolution (Confocal).



sibility



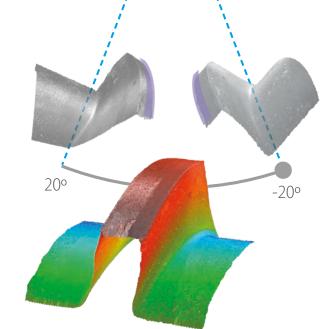
Markets and applications

- Aerospace & Automotive
- Forensics
- Gears
- Medical Devices
- Micromanufacturing
- Sharp Objects
- Surface Finish
- Tooling Industry
- Watch Manufacturing

Rotational stage

consists of a high-precision motorized rotating A axis with 360° of endless rotation, 10 arc sec positioning repeatability, a motorized B axis, -30° to 110°, 0.5 arc sec resolution, with limit switch. It is equipped with a System3R clamping system.

The S neox Five Axis makes it possible to take automatic 3D surface measurements at defined positions, and combine them to create a complete 3D volumetric measurement



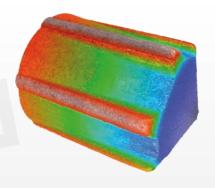
Acomplete 3D measurement

S neox Five Axis is able to measure the sample at different positions of rotation and elevation (perspectives) generating a group of individual measurements. The SensoFIVE software merges all of the surfaces providing a sample surface with high accuracy by using the stacked image information of each single surface measurement. Merging different elevations, the system can provide shape and form information on sharp edges and/or critical surfaces.





Measuring complex surfaces which contain steep angles is very difficult due to shadowing effects that prevent you from obtaining a complete measurement within a single acquisition. It is necessary to tilt the sample in order to measure it from two different positions and combine the two topography results to obtain the complete measurement. Five Axis rotational stage allows the sample to be positioned in opposite directions to make the entire surface visible. The system will acquire the individual measurements and then, it will merge them automatically to get the complete 3D volumetric measurement.



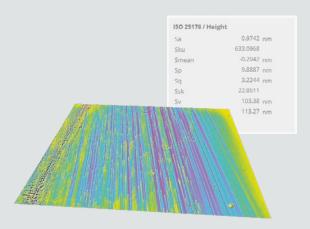
Multiple axis positions, measurements without limitation

Measuring different parts of the sample with one click is possible thanks to automation routines. A user-friendly interface allows you to find the measurement position without any constraints. Then focus on the critical parts of your sample and add them to the automation routine. Finally click Acquire to obtain all parts measured with one single click. This is an incredibly fast and easy way to automate the measurement routines.









Accurate and reliable surface finish measurements

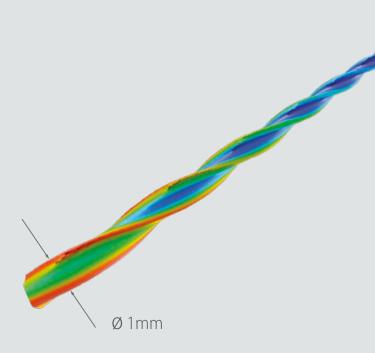
Our Confocal and Interferometry technologies allow you to measure surfaces with any kind of roughness from extremely rough (typical of additive manufacturing applications) to highly reflective surfaces of the order of 1 A as a diamond mirror-like surface. Converting our system into repetitive and traceable, according to NPL, NIST and PTB roughness standards. Ai Focus Variation technology provides a quick and easy response for measuring outstanding slopes independently of the objective lenses.



Overcoming the limitations of Focus Variation

S neox Five Axis is able to measure the shape and surface finish. Focusing on the shape, the system is able to measure samples with small diameters up to 0.5 mm and cutting edge radius up to 150 nm. Using Confocal technology and high numerical apertural (0.95) allows you to measure small cutting edge radius.

um versatility



Non-contact surface assessment

Ø 350µm

Designed as a high-performance 3D optical profiler from the outset, S neox Five Axis outperforms all existing optical profilers by combining three techniques – Confocal (best for surfaces with high slope), Interferometry (yields the highest vertical resolution) and Ai Focus Variation (measure shape in mere seconds) – in the same sensor head without any moving parts.

Discover any geometric deviation or tolerance limit of your measured part

Sensofive

Automatic Measurement Recipes

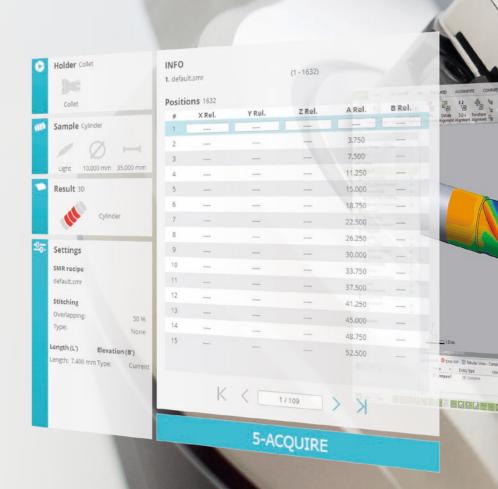
Five Axis measurement recipes allow you, the user, to capture the entire surface area in order to measure critical dimensions (angles, radius, contour), along with surface finish acording to ISO 25178 (form and roughness) and volume. Automated measurement routines can be executed for batch processing of parts for QA/QC applications.

ISO parameters

SensoFIVE is compliant with several ISOs. A complete selection of ISO 3D areal surface texture parameters is available: height, spatial, hybrid, functional and volumetric parameters.

Multiple exportable formats

All data is exportable as PLY, STL, STEP, IGES, g3d, xyz and PCD files.





Hardware

Ring light

The Ring light is based on an LED ring for illuminating samples in a uniform and efficient way. It is mounted above and around the objective, the ring light provides increased signal for both Confocal and Ai Focus Variation techniques. This ensures proper illumination at the focal plane.

Large range of objective lenses

The S neox uses premium CF60-2 Nikon objective lenses that have been designed to correct for chromatic aberrations, to produce sharp, flat and clear images with high contrast and resolution by providing the largest available working distance for each NA. S neox Five Axis is equipped with these lenses for save and easy operation.









Assorted holders & collets

Different types of holders are available depending on the sample. For rotational samples, a collet holder (multiple options are available on request) with fifteen collets, and for the others, a flat holder. It also includes a calibration pack composed of a flat mirror and a calibration specimen.



Objective lenses

Brightfield Interferometri

	MAG	5X	10X	20X	50X	100X	150X	2.5X	5X	10X	20X	50X	100X
	IWAU	<i>3</i> /\	10/	20/	J0/\	100/	1307	2.5/\	J/\	10/	20/	J0/\	1007
	NA	0.15	0.30	0.45	0.80	0.90	0.90	0.075	0.13	0.30	0.40	0.55	0.70
	WD (mm)	23.5	17.5	4.5	1.0	1.0	1.5	10.3	9.3	7.4	4.7	3.4	2.0
	FOV¹ (μm)	3378x2826	1689x1413	845x707	338x283	169x141	113x94	6756x5652	3378x2826	1689x1413	845x707	338x283	169x141
	Spatial sampling² (μm)	1.38	0.69	0.34	0.13	0.07	0.05	2.76	1.38	0.69	0.34	0.13	0.07
ı	Optical resolution³ (µm)	0.94	0.47	0.31	0.18	0.16	0.16	1.87	1.08	0.47	0.35	0.26	0.20

Confocal / Ai Focus Variation PSI / ePSI / CSI

		20		0 0 0 0 0 0 0 0 0 0 0 0 0 0 0 0 0 0 0 0					,	0., 00.			
System noise⁴ (nm)	100	30	8	4	3	2		PSI/ePSI 0.1	I nm (0.01 nm	n with PZT)	CSI 1 nm		
Maximum slope ⁵ (°)	9	17	27	53	64	64	4	7	17	24	33	44	

System specifications

Measuring principle Confocal, PSI, ePSI, CSI, Ai Focus Variation and Thin Film Observation types Brightfield, Sequential Color RGB, Confocal, Interferential Phase Contrast Image, 3D, 3D thickness, profile and coordinates Measurement types 5Mpx: 2448x2048 pixels (60 fps) Total magnification (27" screen) 60X - 21600X Display resolution Field of view from 0.018 to 6.7 mm (single shot) Max. Extended measuring area 10x12 (Max. Resolution); 175x175 (Low resolution) (500 Mpx) Confocal frame rate 60 fps (5Mpx); 180 fps (1.2 Mpx) Vertical scan range coarse Linear stage: 40 mm range; 5 nm resolution Vertical scan range fine Piezoelectric scanner with capacitive sensor: 200 µm range; 1.25 nm resolution Max. Z measuring range PSI 20 µm; CSI 10 mm; Confocal & Ai Focus Variation 34 mm XY stage range Motorized: 154x154 mm LED light sources Red (630 nm); green (530 nm); blue (460 nm) and white (575 nm; center) Ring light illumination Green ring light compatible with 6 position nosepiece Nosepiece 6 position fully motorized Sample reflectivity 0.05 % to 100% Sample weight up to 3 Kg User Management rights Administrator, supervisor, advanced operator, operator SensoMAP, SensoPRO, SensoMATCH, SensoCOMP, Geomagic® Optional Advanced Software Analysis Line Voltage 100-240 V AC; frequency 50/60 Hz single phase Computer Latest INTEL processor; 3840x2160 pixels resolution (4K) (27") Microsoft Windows 10, 64 bit Operating system Dimensions HxWxD 945 x 635 x 610 mm (37.2 x 25.0 x 24.0 in) 77 kg (170 lbs) Weight1: Temperature 10 °C to 35 °C; Humidity <80 % RH; Altitude <2000 m Environment

Accuracy and repeatability⁶

Standard	Value	U, σ	Technique
Step height	48600 nm	U = 300 nm $\sigma = 10 \text{ nm}$	Confocal & CSI
	7616 nm	U = 79 nm $\sigma = 5 \text{ nm}$	Confocal & CSI
	941.6 nm	$U=7 \text{ nm}$ $\sigma=1 \text{ nm}$	Confocal & CSI
	186 nm	U = 4 nm $\sigma = 0.4 \text{ nm}$	Confocal & CSI
	44.3 nm	$\begin{array}{l} U = 0.5 \text{nm} \\ \sigma = 0.1 \text{nm} \end{array}$	PSI
	10.8 nm	U = 0.5 nm $\sigma = 0.05 \text{ nm}$	PSI
Areal roughness (Sa) ⁷	0.79 μm	$U = 0.04 \mu m$ $\sigma = 0.0005 \mu m$	Confocal, AiFV & CSI
Profile roughness (Ra) ⁸	2.40 µm	$U = 0.03 \mu m$ $\sigma = 0.002 \mu m$	Confocal, AiFV & CSI
	0.88 µm	$U = 0.015 \mu \text{m}$ $\sigma = 0.0005 \mu \text{m}$	Confocal, AiFV & CSI
	0.23 μm	$U = 0.005 \mu \text{m}$ $\sigma = 0.0002 \mu \text{m}$	Confocal, AiFV & CSI

Rotational stage⁹

Max. measurable diameter	200 mm
Max. clamping diameter ¹⁰	20 mm
Max. workpiece weight	3 Kg
Accuracy (A)	5 Arc sec/º
Bidirectional repeatability (A)	10 Arc sec
Resolution (B)	0.5 Arc sec
Straightness error ¹¹	3.6 µm/40 mm
Parallelism error ¹¹	53.9 μm/40 mm
Flatness error ¹²	20 μm

¹ Maximum field of view with 3/2" camera and 0.5X optics. 2 Pixel size on the surface. 3 L&S: Line and Space. Values for blue LED. 4 System noise measured as the difference between two consecutive measures on a calibration mirror placed perpendicular to the optical axis. For interferometric objectives, PSI, 10 phase averages with vibration isolation activated. The 0.01 nm are achieved with Piezo stage scanner and temperature controlled room. Values for green LED (white LED for CSI). Resolution HD. 5 On smooth surfaces, up to 71°. On scattering surfaces, up to 86°. 6 Objective used for Confocal and Ai Focus Variation 50X 0.80 NA and for CSI and PSI 50X 0.55NA. Resolution 1220x1024 pixels. All measurements are done using PZT. Uncertainty (U) according to ISO/IEC guide 98-3:2008 GUM:1995, K=1,96 (level of confidence 95%), or according to 25 measures. 7 Area of 1x1 mm. 8 Profile of 4 mm length. 9 All values according to ISO1101 at 20°C +/- 1° in an anti-vibration environment. 10 ER32 collet holder. 11 St Flatness deviation according to ISO25178-2 taken on a SiC reference flat mirror and 20X objective in Confocal acquisition mode. 12 All values are taken with a 20X objective in Confocal acquisition mode and 40 mm evaluation length. 13 Adjustable stand with H105 XY stage.





SENSOFAR is a leading-edge technology company that has the highest quality standards within the field of surface metrology

Sensofar Metrology provides high-accuracy optical profilers based on confocal, interferometry and focus variation techniques, from standard setups for R&D and quality inspection laboratories to complete non-contact metrology solutions for in-line production processes. Sensofar Group is headquartered in Barcelona, also known as a technology and innovation hub in Europe. The Group is represented in over 30 countries through a global network of partners and has its own offices in Asia, Germany and the United States.

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